

Appl. No. 10/827180

In the Claims:

Listing of all claims:

1-42. (Cancelled.)

43. (Previously Added) An apparatus for processing elongate material continuously advancing along a processing path, comprising:

at least a first pair of cyclically driven tools following an orbital movement, between which the material passes as it moves along the processing path, and which synchronously engage opposite faces of the material during a portion of the orbital movement and move at the same linear speed as the material when in contact therewith, and return upstream along the orbital movement to re-engage the advancing material and repeat the processing cycle, wherein each tool is cantilevered on a near end transversely of the processing path from a tool drive located adjacent a near edge of the processing path and further wherein the tool drive for each tool supports the tool for orbital movement around a drive axis that extends transversely of the processing path such that the orbital movement forms a circle; and

a pair of passive devices effective during a portion of the orbital movement, each located near a distal end of one of the pair of tools, to affect the position of the distal end.

44. (Currently Amended) The apparatus of claim 43 ~~41~~, wherein the pair of passive devices is effective during at least all of the portion of the orbital movement.

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45. (Currently Amended) The apparatus of claim 44 ~~42~~, wherein the pair of passive devices is effective during at least the time the material is engaged.

46. (Currently Amended) The apparatus of claim 45 ~~43~~, wherein the pair of passive devices includes a spring.

47. (New) The apparatus of claim 46 ~~44~~, further comprising a second pair of opposing passive devices, each mounted near the near end of each tool carrier, effective during at least part of the portion of the orbital movement, wherein the second pair of passive devices affects the path of the pair of tools mounted on the carrier.

48. (Currently Amended) The apparatus of claim 47 ~~20~~, further comprising a second pair of cyclically driven tools following a second orbital movement, between which the material passes as it moves along the processing path, and which synchronously engage opposite faces of the material during a portion of the second orbital movement and move at the same linear speed as the material when in contact therewith, and return upstream along the second orbital movement to re-engage the advancing material and repeat the processing cycle, wherein each of the second pair of tools is out of phase with the first pair, and cantilevered on the distal end of the second pair transversely of the processing path from a second tool drive located adjacent the distal edge of the processing path and further wherein the second tool drive for each second pair of tools second drive axis that extends transversely of the processing path such that the orbital movement forms a circle, and a third pair of passive devices effective during a portion of the second orbital movement, each located near the near distal

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end of one of the second pair of tools, to affect the position of the near end.

49-51. (Cancelled.)